

ABSTRACT

There is provided a vacuum deposition apparatus which is arranged to surely separate in terms of atmosphere a deposition chamber having disposed therein a deposition unit from such an adjacent chamber as is adjacent to the deposition chamber and as is inside the main chamber, at the time of depositing on such a part of the sheet-like base material as is wound around a can-roller.

The apparatus has: a main chamber 1 with a base material transportation means, and a can-roller 2; and a deposition unit Vu for depositing on such a portion of the sheet-like base material Sw as is wound around the can-roller 2. Inside the main chamber there are further provided: first partition walls 75 partitioning a deposition chamber which stores therein the deposition unit; and second partition walls 7a, 7b disposed in continuation to the first partition walls so as to cover such outer cylinder parts of the can-roller as are positioned on both circumferential sides of the deposition unit while leaving a first gap Gp1 that curves at the curvature. The deposition chamber Vs and such an adjacent chamber As as is adjacent to the deposition chamber and as is inside the main chamber are in communication with each other with the first gap serving as a boundary such that a conductance between the deposition chamber and the adjacent chamber is determined by the second partition walls.